

Docket No.:0756-7244

1FW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inter PATENT application of )  
Koichiro TANAKA, et al. )  
Serial No. 10/749,505 ) Group Art Unit: 2828  
Filed: January 2, 2004 ) Examiner: Minsun Harvey  
For: LASER IRRADIATION METHOD, METHOD )  
FOR MANUFACTURING SEMICONDUCTOR )  
DEVICE, AND LASER IRRADIATION SYSTEM )

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with  
The United States Postal Service with sufficient postage as First  
Class Mail in an envelope addressed to: Commissioner for Patents,  
P. O. Box 1450, Alexandria VA 22313-1450, on June 1, 2005

*Randy L. Kuss*

**REQUEST FOR STATUS**

Honorable Commissioner of Patents


P. O. Box 1450

Alexandria VA 22313-1450

Sir:

To date the undersigned attorney of record has received no action in the above-identified patent application. Please provide the undersigned with a status report of the application in writing.

Respectfully submitted,

  
Eric J. Robinson  
Reg. No. 38,285

Robinson Intellectual Property Law Office, P.C.  
PMB 955  
21010 Southbank Street  
Potomac Falls, Virginia 20165  
(571) 434-6789  
(571) 434-9499 (Fax)